



# Charting Electron Energy Loss Spectra with Machine Learning

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# From the Higgs boson to quantum materials



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#### results based on:

- Roest, van Heijst, Maduro, Rojo, Conesa-Boj, Ultramicroscopy (2021)
- van Heijst, Mukai, Okunishi, Hashiguchi, Maduro,
  Roest, Rojo, Conesa-Boj, Annalen der Physiek (2021)
- Postmes, Brokkelkamp, van Heijst, ter Hoeve, Maduro, Rojo, Conesa-Boj, *in preparation*



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# **Electron Energy Loss Spectroscopy**

EELS: monitor **energy losses** suffered by the electrons from a Transmission Electron Microscope (TEM) beam upon **interaction with the sample** 



- Challenge: EELS measurements affected by huge background (zero-loss peak) at lowenergy losses from elastic scatterings: complicates interpretation of material properties!
- Solution: parametrise backgrounds from data using Deep Neural Networks and Monte Carlo sampling to remove them in a model-independent manner

#### **ML-driven background subtraction in HEP**





outputs: data-driven background model

- Learn from data underlying physical laws and parametrise them with neural nets
- Estimate model uncertainties from Monte Carlo replica method: train a large number of models on *fake replicas* of actual data
- Reliable extrapolation to different datasets and ranges of the input variables

# A ML model for EELS backgrounds



#### The Monte Carlo replica method

Generate Monte Carlo replicas of the original data points with multi-Gaussian distribution with central values and covariance matrices taken from the input measurements

$$I_{\mathrm{ZLP},i}^{(\mathrm{art})(k)} = I_{\mathrm{ZLP},i}^{(\mathrm{exp})} + r_i^{(\mathrm{stat},k)} \sigma_i^{(\mathrm{stat})} + \sum_{j=1}^{n_{\mathrm{sys}}} r_{i,j}^{(\mathrm{sys},k)} \sigma_{i,j}^{(\mathrm{sys})} , \quad \forall i , \quad k = 1, \dots, N_{\mathrm{rep}} ,$$

Frain a NN model on each replica from the minimisation of the log-likelihood

$$E^{(k)}\left(\{\theta^{(k)}\}\right) = \frac{1}{n_{\text{dat}}} \sum_{i=1}^{n_{\text{dat}}} \left(\frac{I_{\text{ZLP},i}^{(\text{art})(k)} - I_{\text{ZLP},i}^{(\text{mod})}\left(\{\theta^{(k)}\}\right)}{\sigma_i^{(\text{exp})}}\right)^2,$$

We end up with a sampling of the probability density in the space of NN models, from which we can compute e.g. the variance of the predicted ZLP intensity for arbitrary inputs

$$\sigma_{I_{\rm ZLP}}^{\rm (mod)}(\{z_1\}) = \left(\frac{1}{N_{\rm rep}} - 1 \sum_{k=1}^{N_{\rm rep}} \left(I_{\rm ZLP}^{\rm (mod)(k)} - \left\langle I_{\rm ZLP}^{\rm (mod)}\right\rangle\right)\right)^{1/2}$$

state of the art for error propagation in deep-learning models

### **Extrapolation to new TEM operation conditions**

Key property of ML: **prediction** to different ranges of input parameters



- Train ZLP model for specific values of TEM operation parameters, e.g. electron beam energy and then inter/extrapolate outside training range
- **M** The model **uncertainties increase** when our prediction is not reliable and more data needed
- Important: no assumptions of functional dependence of background model with input variables

# **Band gap extraction in polytypic WS<sub>2</sub>**



 $\mathbf{v}$  Apply to **nanoflowers** composed by **polytypic WS**<sub>2</sub> (a 2D quantum material)  $\mathbf{v}$  First extraction of band gap in this material from fit to subtracted EEL spectra

$$I_{\text{inel}}(\Delta E) \simeq A \left(\Delta E - E_{\text{BG}}\right)^b \qquad E_{\text{BG}} = 1.6^{+0.3}_{-0.2} \,\text{eV}\,, \quad b = 1.3^{+0.3}_{-0.7}\,.$$

☑ ML-subtracted spectra make possible mapping **exciton transitions** down to 1.5 eV

# **Band gap extraction in polytypic WS<sub>2</sub>**



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# **ML analysis of spectral images**

STEM intensity sample



- EELS spectral image contains up to O(10<sup>5</sup>) individual spectra
- ✓ Use unsupervised learning (*K*-means clustering) to identify clusters of pixels with comparable sample thickness and combine them for the (supervised) NN training
- Simultaneous determination of physical properties across the **whole nanostructure** with their **uncertainties:** thickness, band gap, position and width of plasmonic and excitonic resonances,...

# Summary and outlook

Machine learning algorithms offer exciting avenues to improve and boost data interpretation in electron microscopy and related techniques

- The combination of deep learning models and Monte Carlo replica methods make possible assumption-free, faithful background subtraction in EELS spectra
- One can reliable predict the shape and magnitude of these backgrounds for other operation conditions beyond those used in the training
- The methodology can be applied to any other problem where large (multi-dimensional) backgrounds needs to be removed in order to access the relevant physical information

results obtained with **EELSfitter** code, publicly available in GitHub:

https://github.com/LHCfitNikhef/EELSfitter